WHAT IS CLAIMED IS:

1. A liquid-jet head comprising:

a passage-forming substrate on which pressure generating chambers communicating with nozzle orifices are defined, and a piezoelectric element composed of a lower electrode, a piezoelectric layer and an upper electrode, which are provided on the passage-forming substrate while interposing a vibration plate therebetween,

wherein, both ends of the piezoelectric layer in its width direction at a pressure generating chamber side are positioned in a region facing the pressure generating chamber, and a relationship between a width x of the piezoelectric layer at the pressure generating chamber side and a width y of the pressure generating chamber at the vibration plate side satisfies $0.75 \leq x/y \leq 1$.

2. The liquid-jet head according to claim 1,

wherein the width x of the piezoelectric layer at the pressure generating chamber side and the width y of the pressure generating chamber at the vibration plate side are equal.

3. The liquid-jet head according to claim 1,

wherein the width y of the pressure generating chamber at the vibration plate side is defined by outer peripheries at both sides of a space portion in its width direction, the space being provided at a periphery of an opening of the pressure generating chamber at the vibration plate side.

4. The liquid-jet head according to claim 1,

wherein the pressure generating chambers are formed in

a single crystal silicon substrate by anisotropic etching, and each layer of the piezoelectric element is formed by deposition and a lithography method.

5. A liquid-jet apparatus comprising:

the liquid-jet head according to any one of claims 1 to 4.